

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

VAN DER WERF et al.

Application No.: TO BE ASSIGNED

Group Art Unit: UNKNOWN

Filed: July 14, 2003

Examiner: UNKNOWN

Title: LITHOGRAPHIC APPARATUS AND  
DEVICE MANUFACTURING METHOD

\* \* \* \*

July 14, 2003

**INFORMATION DISCLOSURE STATEMENT**

Hon. Commissioner of Patents  
Washington, D. C. 20231

Sir:

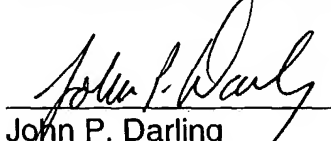
Attached is a Form PTO-1449 listing the enclosed documents.

The listed documents were cited in the attached European Search Report issued in a counterpart European application.

This Information Disclosure Statement is intended to be in full compliance with the rules, but should the Examiner find any part of its required content to have been omitted, prompt notice to that effect is earnestly solicited, along with additional time under Rule 97(f), to enable Applicant to comply fully.

Consideration of the foregoing and enclosures plus the return of a copy of the herewith Form PTO-1449 with the Examiner's initials in the left column per MPEP 609 along with an early Action on the merits of this application are earnestly solicited.

Respectfully submitted,  
PILLSBURY WINTHROP LLP



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FORM PTO-1449 (modified)  
 To: U.S. Department of Commerce  
 (PW FORM PAT-1449)  
 Patent and Trademark Office

Att'y.  
 Dkt. No.

M#

Client Ref.

304800

P-0342.010-US

# **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

Applicant: VAN DER WERF et al.

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of

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Examiner:

Group Art Unit:

## **U.S. PATENT DOCUMENTS**

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
	AR	4,613,230	IWAI			
	BR	4,856,905	NISHI			
	CR	6,142,641	COHEN et al.			
	DR	6,151,120	MATSUMOTO et al.			
	ER					
	FR					
	GR					
	HR					
	IR					

## **FOREIGN PATENT DOCUMENTS**

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
	JR	5-160001	06/1993	JAPAN	MIZUTANI	X		
	KR							
	LR							
	MR							
	NR							
	OR							
	PR							
	QR							
	RR							
	SR							

## **OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

TR	Chaudhuri et al., "Alignment of a multilayer-coated imaging system using extreme ultraviolet Foucault and Ronchi interferometric testing," <i>J. Vac. Sci. Technol. B</i> 13(6):3089-3093 (1995), XP 000558379			
UR	Vaidya et al., "Extreme Ultraviolet Lithography for 0.1 $\mu$ m Devices," <i>VLSI Technology, Systems and Applications</i> , 1999. International Symposium on Taipei, Taiwan, 8-10 June 1999, Piscataway, NJ, pp. 127-130, XP 10347511			
VR				
WR				
XR				
YR				
ZR				
AAR				

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.